

# Interference Search

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L2	0	((semiconductor adj wafer) and inspecting and damping and gap and free).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/19 09:53
L3	0	((semiconductor adj wafer) and inspecting and damping and gap).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/19 09:54
L4	0	(semiconductor and wafer and inspecting and damping and gap).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/19 09:54
L5	2	(semiconductor and wafer and inspecting and damping).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/09/19 09:54